



Thin Film Transistors: Material, Structure and Application

Guest Editor:

Prof. Dr. Hyuck-In Kwon

School of Electrical and
Electronics Engineering, Chung-
Ang University, Seoul 06974,
Korea

Deadline for manuscript
submissions:

closed (20 March 2022)

Message from the Guest Editor

Dear Colleagues,

Since the first report on cadmium selenide thin-film transistors (TFTs) by Paul. K. Weimer in 1962, various semiconductor materials have been used for channel materials of TFTs such as amorphous silicon, polycrystalline silicon, organic semiconductors, and oxide semiconductors. To date, TFTs have been used for various applications such as active-matrix liquid crystal display, active-matrix organic light-emitting diode displays, X-ray detectors, chemical sensors, bio sensors, and memory devices. However, to use the TFTs in more diverse applications, it is crucial to further improve the electrical performance and stability of TFTs. This special issue calls for innovative latest research results on TFTs which can be helpful in expanding their application area.

Prof. Dr. Hyuck-In Kwon
Guest Editor





Editor-in-Chief

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Author Benefits

Open Access: free for readers, with article processing charges (APC) paid by authors or their institutions.

High Visibility: indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

Journal Rank: JCR - Q2 (*Chemistry, Analytical*) / CiteScore - Q2 (*Mechanical Engineering*)

Contact Us

Micromachines Editorial Office
MDPI, St. Alban-Anlage 66
4052 Basel, Switzerland

Tel: +41 61 683 77 34
www.mdpi.com

mdpi.com/journal/micromachines
micromachines@mdpi.com
[X@micromach_mdpi](https://x.com/micromach_mdpi)